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520.34692V17

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: SORAKA et al

Serial No.: 10/826,386

Filed: April 19, 2004

For: Vacuum Processing Apparatus And Semiconductor
Manufacturing Line Using The Same

Art Unit: 3652

Examiner: T. Brahan

PRELIMINARY AMENDMENT

Mail Stop: Amendment (No Fee)
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 16, 2004

Sir:

The following amendments are respectfully requested in connection with the
above-identified application, as listed below and as set forth on the following pages:

Amendments to the Claims; and

Remarks are included following the amendments.

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